

Supporting Information for

Multiscale Modelling of the Electrostatic Impact of Self-Assembled Monolayers used as Gate Dielectric Treatment in Organic Thin-Film Transistors

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Molecular Dynamics (MD):

Force Field

The charges and Lennard-Jones parameters for silicon and oxygen atoms in SiO₂ were borrowed from the force field by Cygan et al.¹. Lennard-Jones parameters and bonding interactions for OTS and FDTS molecules were taken from the classic AMBER force field², except for the LJ parameters for fluorine atoms, for which we adopted the Mod-OPLS parameters by Song et al.³. Mixed interactions between silica and SAMs were evaluated with Lorentz-Berthelot rules. The torsional profiles for -Si-CH₂-, -CH₂-CH₂-, -CH₂-CF₂-, and -CF₂-CF₂- rotations were obtained by constrained wB97XD/aug-cc-pVTZ minimization carried out on the fragments Si(OH)₃-CH₂CH₃, CH₃CH₂-CH₂CH₃, CH₃CH₂-CF₂CF₃ and CH₃CH₂CF₂.CF₃, respectively (Figure S1). It is worth noting that while the torsion between a fluoroalkyl and an alkyl segment is very similar to the well-known alkyl-alkyl torsion, the torsion between two fluorinated segments is more complex, featuring three minima at about 55, 95, and 165 degrees. These torsional potentials were used to re-parameterize the corresponding terms in the molecular mechanics force field (see reference⁴ for the details of the procedure) and obtain a more realistic description of the SAMs conformation. Atomic charges for OTS and FDTS were derived from quantum-chemical calculations carried out with the program Gaussian G09⁵ with DFT at the wB97XD//aug-cc-pVTZ level of theory⁶ (Figure S1). In order to maximize the similarity with the chemical structure of SAMs used experimentally on SiO₂, the calculations were carried out for R-tri-hydroxyl-silanes (Figure S2).

We assumed that all tri-hydroxyl-silane groups are linked to the SiO₂ surface by single Si-O-Si(OH)₂-R bonds. Electro-neutrality in the system was maintained by replacing an hydroxyl group on the surface -Si-OH with a SAM molecule -Si-O-Si(OH)₂-R (with R alkylated or fluorinated, see figure S2), mimicking the chemical reaction between a trichlorosilane derivative and a SiO₂ substrate, followed by hydroxylation of the remaining chlorine atoms. We prepared first a fully hydroxylated surface of SiO₂ and then replaced randomly chosen surface hydroxyl groups. The “reacted” SAM oxygen atom was endowed with a LJ interaction specific to the silicon surface (the same as Si and O in the silica force field¹), so as to promote a sort of bond formation with the surface Si atoms and to make the two atoms (O for the SAM, Si for the silica)

able to get very close, as in a siloxane bond (about 1.64 Å). This way of modeling the formation of a bond with the surface without explicitly grafting the molecules is commonly used for simulations of thiols on gold⁷ and has the advantage of allowing for the self-assembly of the SAM.

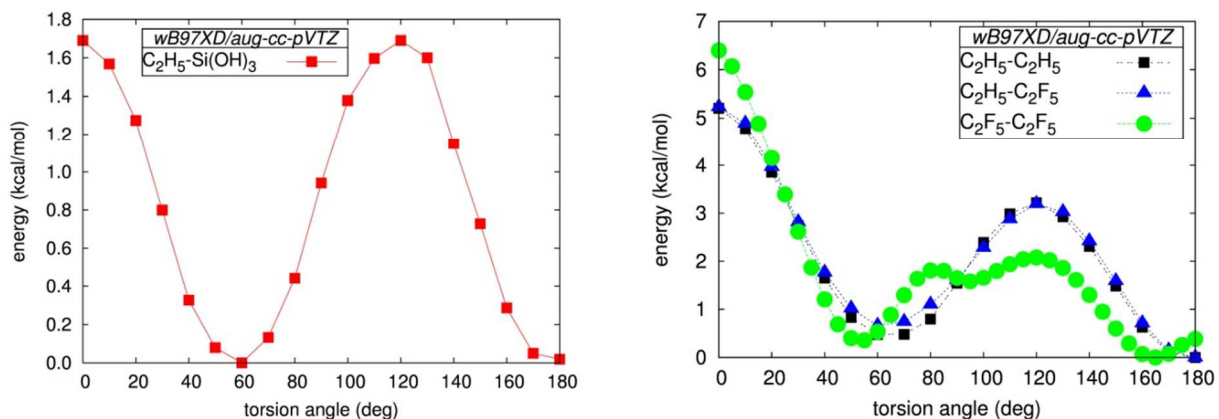


Figure S1: Torsional potentials for -Si-CH₂- (left), -CH₂-CH₂-, -CH₂-CF₂-, and -CF₂-CF₂- rotations (right) calculated at the wB97XD//aug-cc-pVTZ level.

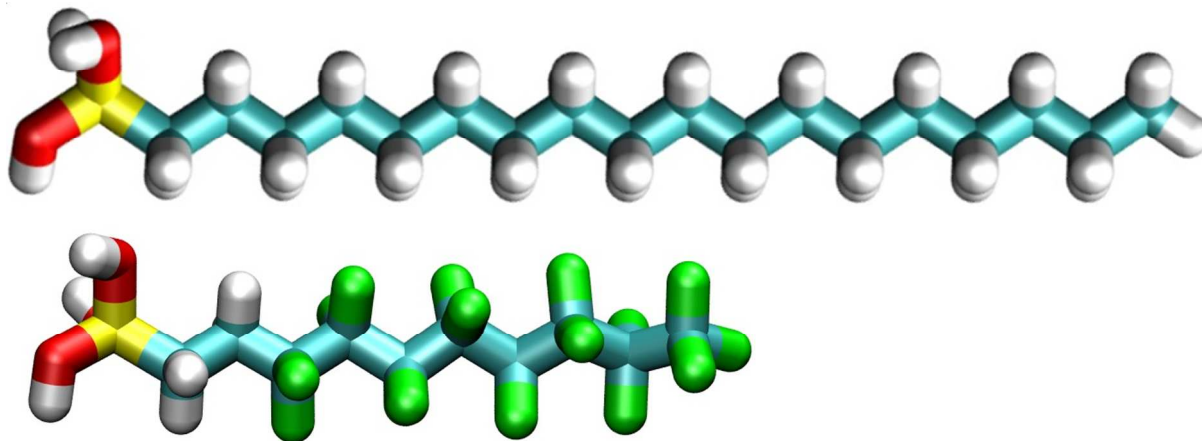


Figure S2: Equilibrium chemical structure of octadecyl tri-hydroxyl silane (OTS, top) and 1H,1H',2H,2H'-perfluorodecyl tri-hydroxyl silane (FDTS, bottom), calculated with DFT at the wB97XD//aug-cc-pVTZ level of theory.

Molecular Dynamics simulation details

An amorphous, dipole-free SiO₂ surface about 60 Å thick and with an area of 89.8x74.9 Å² was created following the procedure described in ⁸, followed by a simulated thermal annealing at 900 K to allow for surface reconstruction. The SAMs were modeled as a slab placed on top of the SiO₂ surface in an orthorhombic box with dimensions 89.8x74.9x200 Å³. Layers of OTS and FDTS molecules were created and superimposed to the existing silicon dioxide surface, yielding coverages of 4.5 and 3.8 molecules/nm², respectively. These values were estimated at full coverage from the lattice vectors of OTS and FDTS in the hexagonal packing arrangement, as obtained from the first-neighbor average distances calculated from previous MD simulations of similar samples with lower surface coverage (4.2 and 3.5 molecules/nm², respectively). At lower coverage in fact the SAMs are not constrained to be crystalline: nevertheless we were able to observe spontaneous crystalline aggregate from which we estimated the molecular areal density at “equilibrium” for crystalline SAMs. A total of 302 molecules of OTS and 256 molecules of FDTS were used to model those SAM. MD simulations were carried out in the NVT ensemble at 300 K with the program NAMD v 2.8. Energy equilibrium was reached in about 110 ns for both samples, followed by a production time of 30 ns. Only the top 15 Å of the SiO₂ surface was let free to move, while the rest of the silica slab was kept fixed for the whole simulation.

We characterized the structure of the two SAMs in terms of orientational order, thickness and tilt angle. The orientational order was measured with the order parameter $P_2 = 3/2 \langle \cos^2 \beta \rangle - 1/2$, where β is the angle measuring the deviation of the orientation of the head-to-tail unit vector of each SAM molecule from the main direction of the alignment (c. f. also ⁴). In the case of perfect alignment P_2 goes to one, while for a random distribution of orientations P_2 is zero. Both SAMs present a high orientational order: OTS is almost perfectly aligned ($P_2=0.97$) while FDTS is a bit more disordered ($P_2=0.86$). However, the main difference between the two structures resides in the direction of this alignment: OTS is tilted of 23 degrees with respect to the surface normal, while FDTS is on average parallel, as shown by the distribution of the tilt angle in Figure S3. The presence of the tilt for OTS is in qualitative agreement with literature data; however, for alkylsilanes, tilt angles measurement are rather scattered and cover a broad range from 10 to 40 degrees⁹, so that we cannot claim a quantitative agreement. In Figure S3 we also plot the SAM density along the direction of the box perpendicular to the silica surface, which can be used to

estimate the SAM thickness. At high coverage, the experimental values are $21 \pm 1 \text{ \AA}$ for OTS (reference ¹⁰, “LB-50” sample) and $13.4 \pm 0.2 \text{ \AA}$ for FDTS¹¹; the widths at half height of our distributions are in rather good agreement with those values. Actually, both the tilt angle and thickness are coverage-dependent and related one to another – in fact, the tilt is often estimated from the ratio between the calculated length of the SAM molecule in its extended conformation and the measured thickness. Using this argument, since the thickness measured for FDTS is $13.4 \pm 0.2 \text{ \AA}$ and the calculated *ab initio* value is 13.3 \AA ¹¹, we can assume that FDTS is not tilted in real SAMs, as shown by our simulations.

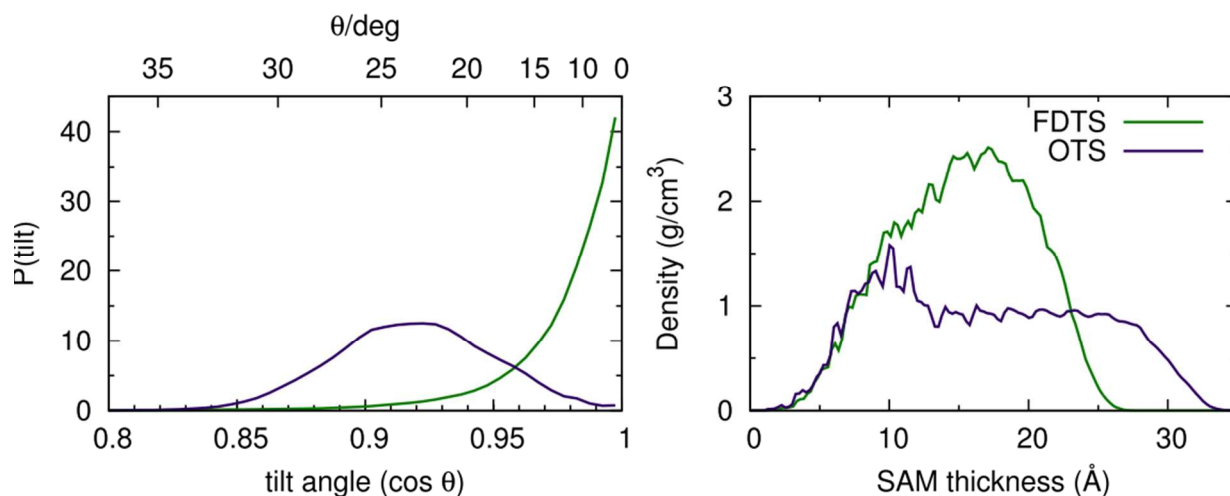


Figure S3: SAM tilt angle distribution for the head-to-tail vector (left), and mass density along the z-coordinate of the simulation box (right) for FDTS (green line) and OTS (blue line).

Device preparation: Pentacene-based OTFTs were fabricated on a doped Si/SiO₂ substrate with an aluminum back-side as a gate contact. The OTS and FDTS SAMs were vapor deposited on the substrate in standard deposition conditions (deposition temperature 140 °C, chamber pressure 8 mbar, deposition time 30-60 min, and silane solution volume 5-10 μl). Before depositing a SAM, the system is baked out at 140 °C for 30-60 minutes under vacuum to remove water and possible residues from a previous deposition. A thin film of pentacene (30 nm) is then deposited on this substrate in ultrahigh vacuum (10^{-9} Torr) by thermal evaporation in a home-built system. To ensure a comparable pentacene growth, the substrate temperature during the deposition was kept at 343 K for SiO₂ and OTS samples and at 323 K for FDTS. After the pentacene deposition,

Au top-contacts (~100 nm) are evaporated through a shadow mask to define the source and drain contacts.

Experimental measurement of surface coverage: The experimental coverage has been studied by total reflection X-ray fluorescence (TXRF) spectroscopy, a surface sensitive technique with extremely low detection limits (down to 10^{10} atoms/cm²)¹². Due to the insensitivity of TXRF to elements lighter than Mg, we choose to characterize a bromo undecyl trichloro silane (BUTS) SAM, containing highly “visible” Br atoms. The nature of the chemical bonding between the trichlorosilane group and SiO_x is not affected by the bromine substitution, and in general bromoalkyl SAMs have rather similar properties to other SAMs like OTS and FDTS^{13–15}, though of course the surface area per molecule is larger due to the bulkiness of Br. Note that although all SAMs contain detectable Si atoms, this signal cannot be efficiently used as it is easily lost in the background signal of the silicon substrate. BUTS was deposited on the SiO₂ substrate using a typical vapor deposition technique. Different pre-treatments of the SiO₂ surface were compared: O₂ plasma, UV/ozone, piranha. From the measured surface density of Br atoms, SAM coverage for different pre-treatments was calculated to be 8%, 20%, and 80% respectively (assuming a molecular area for standing BUTS of 28 Å² - note even that larger values have been estimated on iron oxide¹⁶). The relatively high coverage of the latter sample was confirmed by high contact angle with water (<10° for SiO₂ and 90°±3° for BUTS prepared following piranha treatment). It is also worth noting that for bromine-terminated SAMs the packing density is known to be lower than for HO- or H- terminated ones¹⁷.

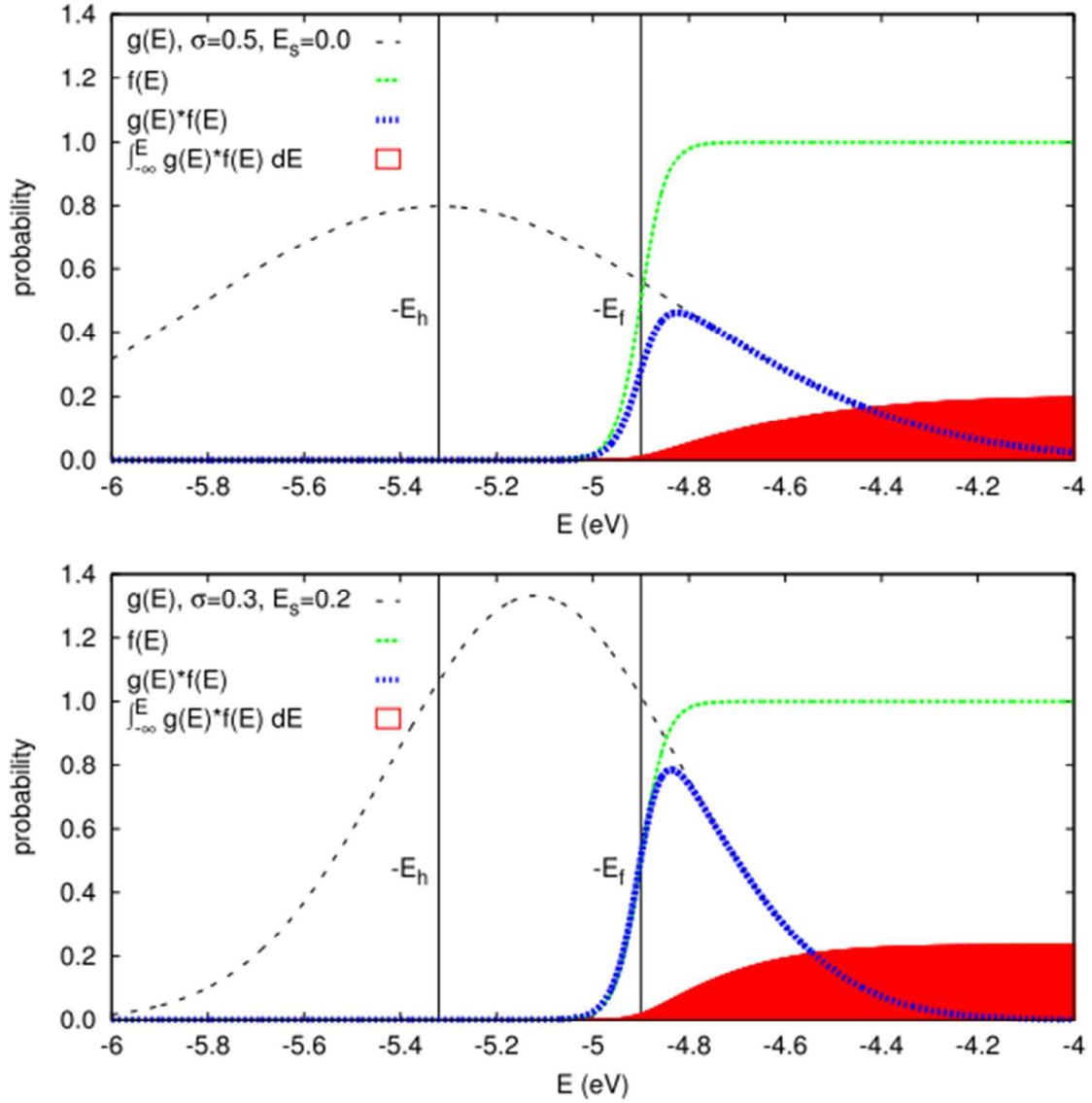


Figure S4: Illustration of the quantities modeled with equations 2-4. The density of states $g(E)$ (Equation 2 in the main text) is a Gaussian function centered at $E_s - E_h$ with standard deviation σ . E_h is the intrinsic hole transport level of pentacene, while $E_f = 4.9$ eV is the Fermi level and $f(E)$ is the Fermi-Dirac distribution function for holes (Equation 3). The interaction $E_s > 0$ of the hole with the SAM decorated surfaces shifts the density of states towards the Fermi level, thus increasing the number N_i of carrier at the interface, given by the integral between $g(E)$ and $F(E)$ (Equation 4 in the main text and red area in this figure). A high roughness of the surface-hole interaction, captured by σ , also contributes to accumulating holes above the Fermi level, as shown by the comparison between the bottom and top panels.

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